

1762

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Woo Sik Yoo  
Assignee: WaferMasters, Inc.  
Title: METHOD OF FORMING AN OXIDE LAYER (As Amended)  
Serial No.: 10/085,498 Filing Date: February 26, 2002  
Examiner: Jolley, Kirsten Group Art Unit: 1762  
Docket No.: M-11549 US Confirmation No. 8701

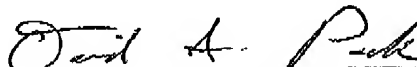
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